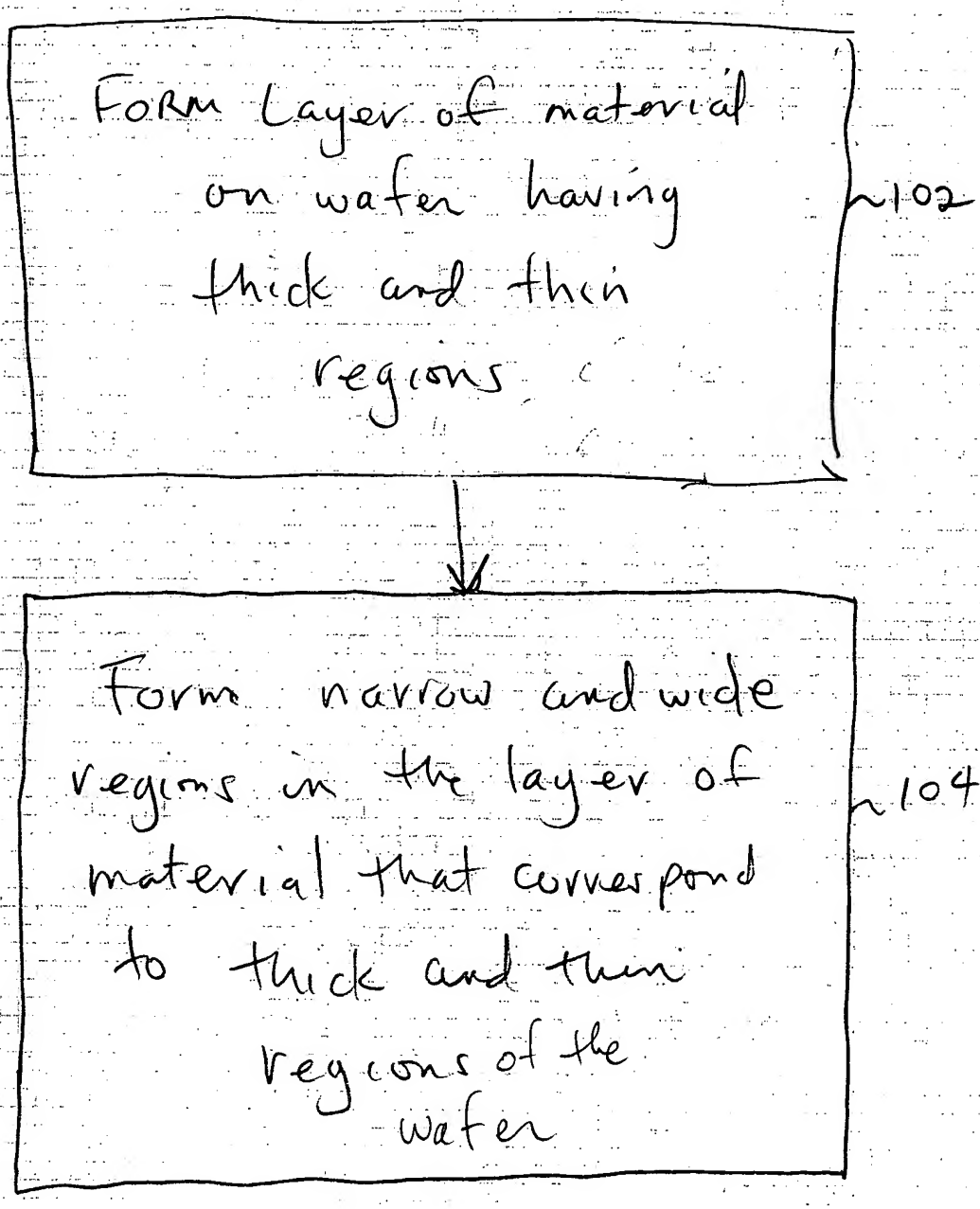

Form Layer of material on wafer having thick and thin regions
102
Form narrow and wide regions in the layer of material that correspond to thick and thin regions of the wafer
104

Figure 1 100

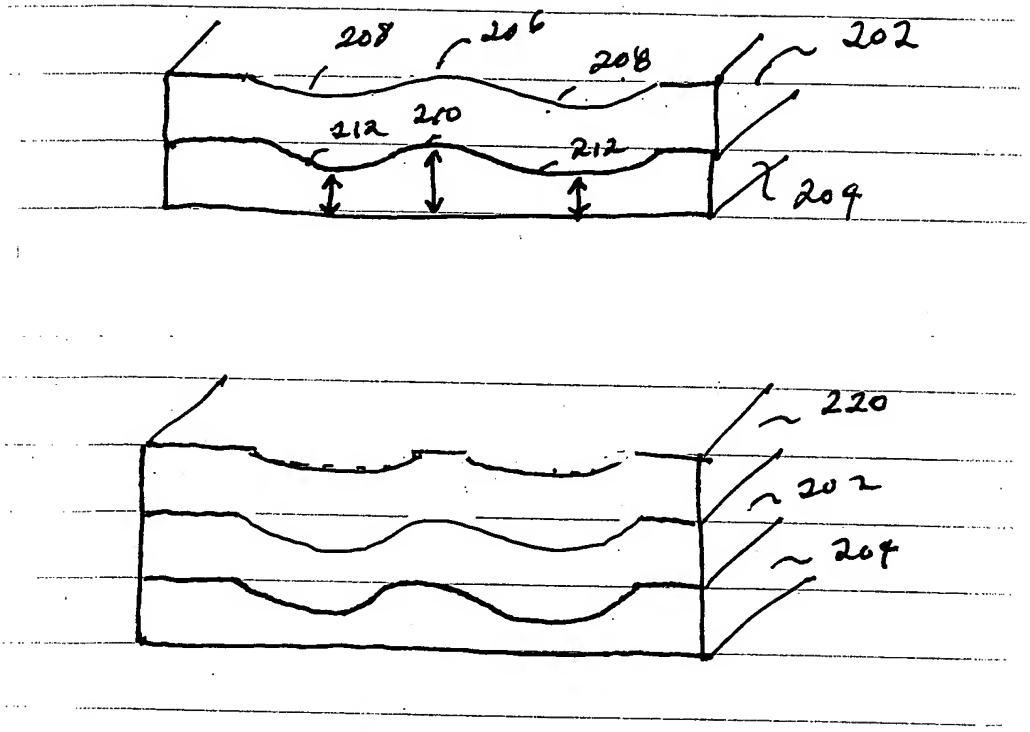

208
206
208
202
212
210
212
204
220
202
204
224
222
220
202
204
202
230
230
204
212
210
228
212

Figure 2

200

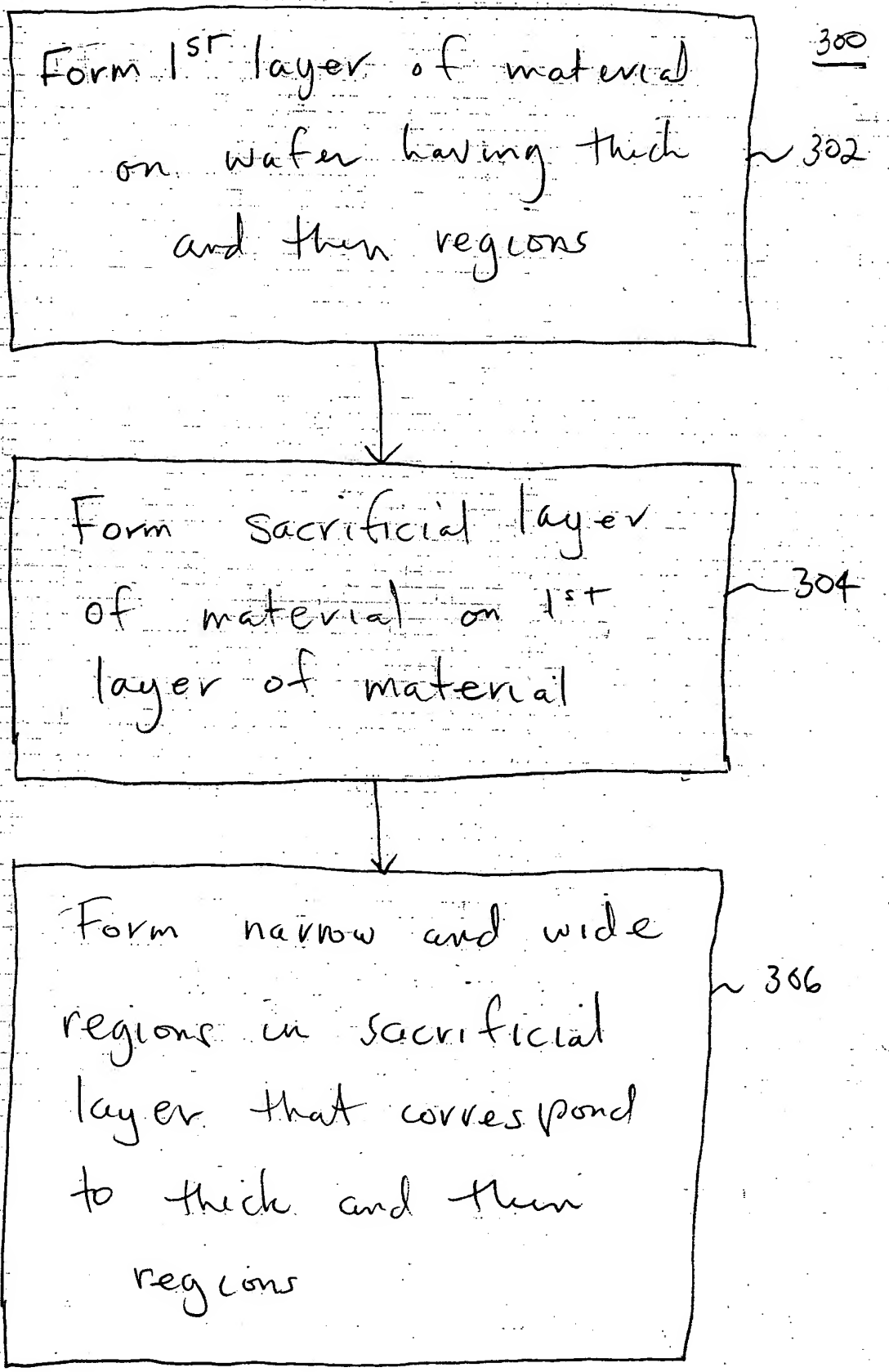

Form 1st layer of material on wafer having thick and thin regions
300
302
Form sacrificial layer of material on 1st layer of material
304
Form narrow and wide regions in sacrificial layer that correspond to thick and thin regions
306

Figure 3

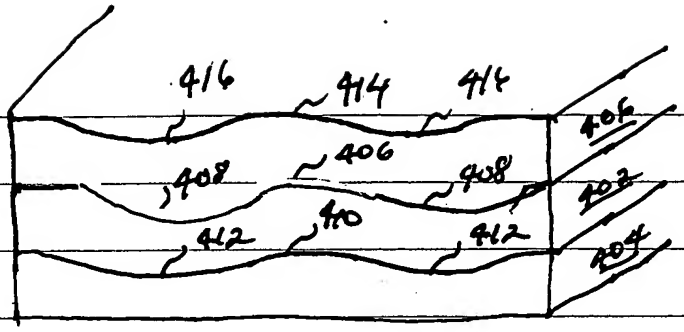
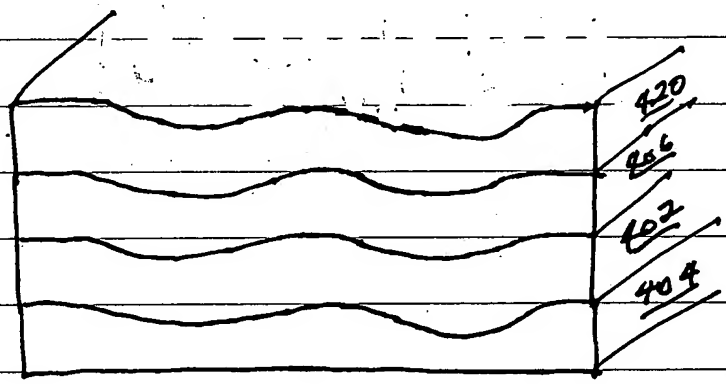
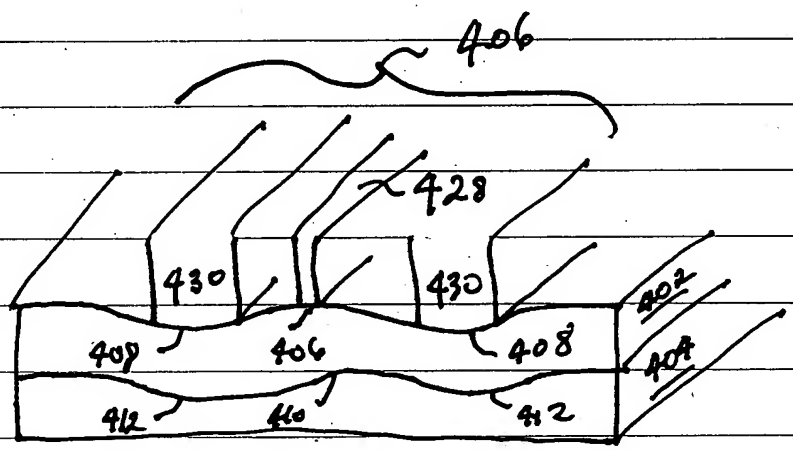

416
414
414
406
408
406
408
402
412
410
412
404

Figure 4


420
406
402
404

400


406
428
430
430
402
408
406
408
404
412
410
412

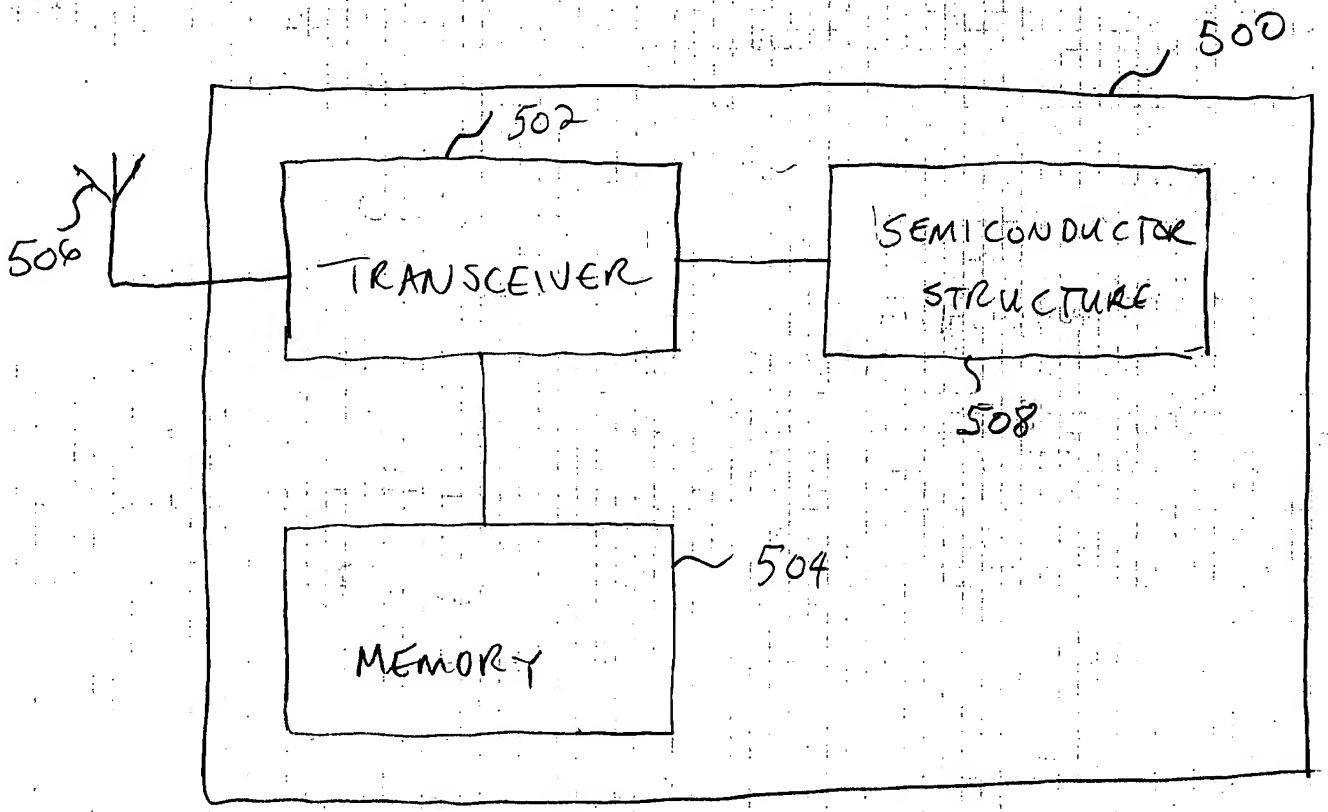

500
502
506
TRANSCEIVER
SEMICONDUCTOR STRUCTURE
508
504
MEMORY

Figure 5